## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): KERBER

Atty. Dkt.: 20-010-DIV

Serial No.: Unknown

Group Art Unit:

Filed: Concurrently herewith

Examiner:

Title: SELF-ALIGNED JUNCTION

PASSIVATION FOR SUPERCONDUCTOR INTEGRATED CIRCUIT

Commissioner for Patents Arlington, VA 22202

Date: April 1, 2004

# INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §1.56, the reference(s) listed on the attached Form PTO-1449 is/are being submitted for consideration by the Examiner without any admission that it/they constitute(s) statutory prior art, or without any admission that it/they contain(s) subject matter that anticipates the invention or renders the invention obvious to a person of ordinary skill in the art.

The Examiner is requested to initial the attached PTO Form-1449 and to return a copy of same to the undersigned attorney as proof that the listed reference(s) has/have been considered and made of record.

Respectfully submitted,

David G. Posz Reg. No. 37,701

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#### \* PATENT APPLICATION

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	APPLICANT	KERBER		
	FILING DATE	April 1, 2004	GROUP	

### REFERENCE DESIGNATION

#### **U.S. PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS

### FOREIGN PATENT DOCUMENTS

TRANSLATION

	DOCUMENT NUMBER	DATE	COUNTRY	NAME	CLASS	SUB CLASS	YES	NO
<u> </u>								

# OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

	H. Kroger et al., "Selective Niobium Anodization Process for Fabricating Josephson Tunnel Junctions," <u>Appl. Phys. Lett.</u> 39(3), 1 August 1981, pp.280-282.				
	S. Morohashi et al., "Self-aligned Contact Process for Nb/AlOx/Nb Josephson Junctions," Appl. Phys. Lett. 48(3), 20 January 1986, pp. 254-256.				
	Y. Tarutani et al., "Niobium-Based Integrated Circuit Technologies," <u>Proceedings of the IEEE</u> , Vol. 77, No. 8, August 1989, pp. 1164-1175.				
	L. Lee et al., "RHEA Process for Fine-Geometry Josephson Junction Fabrication," <u>IEEE Transactions on Magnetics</u> , Vol. 27, No. 2, March 1991, pp. 3133-3136.				
	T. Imamura et al., "A Submicrometer Nb/AlOx/Nb Josephson Junction," J. Appl. Phys. Lett. 64(3), 1 August 1988, pp.1586-1588.				
	S. Hasuo, "High-Speed Josephson Integrated Circuit Technology," <u>IEEE Trans. Magn.</u> , v. 25, no. 2, March 1989, pp. 740 – 749.				
	X. Meng et al., "Very Small Critical Current Spreads in Nb/Al-AlOx/Nb Integrated Circuits Using Low-Temperature and Low Stress ECR PECVD Silicon Oxide Films," IEEE Trans. Appl. Supercon., v. 9, no. 2, June 1999, pp. 3208 – 3211.				
	A. Bhat et al., "A 10 GHz Digital Amplifier in an Ultra-Small-Spread High-Jc Nb/AlOx/Nb Integrated Circuit Process," <u>IEEE Trans. Appl. Supercon.</u> , v. 9, no. 2, June 1999, pp. 3232 – 3236.				
EXAMINER	DATE CONSIDERED				

Rev. 10/94 (Form 3.05)